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1 Precise beam incidence angle control on the VIISTA 810HP

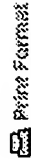
Weeman, J.; Olson, J.; Guo, B.N.; Jeong, U.; Li, G.C.; Mehta, S.;
Ion Implantation Technology. 2002. Proceedings of the 14th International Conference on , 22-27 Sept. 2002
Pages: 276 - 278

[Abstract] [PDF Full-Text (335 KB)] IEEE CNF

2 DC-SQUIDS fabricated by electron beam direct writing

Carelli, P.; Foglietti, V.; Leoni, R.;
Magnetics, IEEE Transactions on , Volume: 23 , Issue: 2 , Mar 1987
Pages: 1087 - 1089

[Abstract] [PDF Full-Text (560 KB)] IEEE JNL



Print Format

- 3 **100 GHz wafer probes based on photoconductive sampling**
Feuer, M.D.; Shunk, S.C.; Smith, P.R.; Nuss, M.C.; Law, N.H.;
 Photonics Technology Letters, IEEE , Volume: 5 , Issue: 3 , March 1993
 Pages:361 - 364

[Abstract] [PDF Full-Text (356 KB)] IEEE JNL

- 4 **Production use of an integrated automatic defect classification (ADC) system operating in a laser confocal/white light imaging defect review station**
Li, J.; McIntyre, M.; Lee, K.; Worster, B.;
 Advanced Semiconductor Manufacturing Conference and Workshop, 1996. ASMC 96 Proceedings. IEEE/SEMI 1996 , 12-14 Nov. 1996
 Pages:107 - 111

[Abstract] [PDF Full-Text (452 KB)] IEEE CNF

- 5 **A (100) silicon stress test chip with optimized piezoresistive sensor rosettes**
Jaeger, R.C.; Suhling, J.C.; Anderson, A.A.;
 Electronic Components and Technology Conference, 1994. Proceedings., 44th , 1-4 May 1994
 Pages:741 - 749

[Abstract] [PDF Full-Text (664 KB)] IEEE CNF

- 6 **Broadband optoelectronic wafer probing**
Feuer, M.D.; Shunk, S.C.; Smith, P.R.; Law, H.H.; Burrus, C.A.; Nuss, M.C.;
 High Speed Semiconductor Devices and Circuits, 1993. Proceedings., IEEE/Cornell Conference on Advanced Concepts in , 2-4 Aug. 1993
 Pages:485 - 493

[Abstract] [PDF Full-Text (556 KB)] IEEE CNF

- 7 **Emissivity correcting pyrometer for temperature measurement in low pressure chemical vapor deposition**
Fordham, M.J.; Gansman, R.F.; Sorrell, F.Y.;
 University/Government/Industry Microelectronics Symposium, 1993., Proceedings of the Tenth Biennial , 18-19 May 1993

Pages: 223 - 228

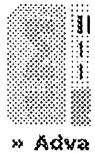
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(calibration<or>calibrated<or>
calibrate<or>calibrating)
<paragraph>wafer<and>
(pattern<or>patterns<or>crucif
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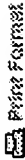
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Pages:867 - 872

[\[Abstract\]](#) [\[PDF Full-Text \(152 KB\)\]](#) [IEEE JNL](#)

3 **Real-time estimation of patterned wafer parameters using in situ spectroscopic ellipsometry**
Galarza, C.G.; Khargonekar, P.P.; Terry, F.L., Jr.;
Control Applications, 1999. Proceedings of the 1999 IEEE International Conference on , Volume: 1 , 22-27 Aug. 1999
Pages:773 - 778 vol. 1

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4 **How good is your calibration? A post-mortem examination and recalibration**
Aguilera, J.; Fisher, B.;
Instrumentation and Measurement Technology Conference, 1990. IMTC-90. Conference Record., 7th IEEE , 13-15 Feb. 1990
Pages:195

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5 **Hybrid optical-electrical overlay test structure [for CMOS]**
Cresswell, M.W.; Allen, R.A.; Linholm, L.W.; Guthrie, W.F.; Gurnell, A.W.;
Microelectronic Test Structures, 1996. ICMTS 1996. Proceedings. 1996 IEEE International Conference on , 25-28 March 1996
Pages:9 - 16

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6 **Analysis of the impact of proximity correction algorithms on circuit performance**
Li Chen; Milor, L.S.; Ouyang, C.H.; Maly, W.; Yeng-Kaung Peng;
Semiconductor Manufacturing, IEEE Transactions on , Volume: 12 , Issue: 3 , Aug. 1999
Pages:313 - 322

[\[Abstract\]](#) [\[PDF Full-Text \(284 KB\)\]](#) [IEEE JNL](#)

7 **A three-step method for the de-embedding of high-frequency S-parameter measurements**

Cho, H.; Burk, D.E.;

Electron Devices, IEEE Transactions on , Volume: 38 , Issue: 6 , June 1991
Pages:1371 - 1375

[Abstract] [PDF Full-Text (444 KB)] IEEE JNL

8 **Production use of an integrated automatic defect classification (ADC) system operating in a laser confocal/white light imaging defect review station**

Li, J.; McIntyre, M.; Lee, K.; Worster, B.;

Advanced Semiconductor Manufacturing Conference and Workshop, 1996. ASMC 96 Proceedings. IEEE/SEMI 1996 , 12-14 Nov. 1996
Pages:107 - 111

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9 **Removal of cable and connector dispersion in time-domain waveform measurements on 40 Gb integrated circuits**

Scott, J.; Behnia, B.; Bossche, M.V.; Cognata, A.; Verspecht, J.; Verbeyst, F.;

Thorn, M.; Scherrer, D.R.;

Microwave Symposium Digest, 2002 IEEE MTT-S International , Volume: 3 , 2-7 June 2002

Pages:1669 - 1672

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10 **An on-wafer fabricated free-chlorine sensor**

van den Berg, A.; Koudelka-Hep, M.; van der Schoot, B.K.; Verney-Norberg, E.;

Krebs, P.; Grisel, A.; de Rooij, N.F.;

Solid-State Sensors and Actuators, 1991. Digest of Technical Papers,

TRANSDUCERS '91., 1991 International Conference on , 24-27 June 1991

Pages:233 - 236

[Abstract] [PDF Full-Text (448 KB)] IEEE CNF

11 **Junction-isolated electrical test structures for critical dimension calibration standards**

Allen, R.A.; Cresswell, M.W.; Linholm, L.W.;
Semiconductor Manufacturing, IEEE Transactions on , Volume: 17 , Issue: 2 , May
2004
Pages:79 - 83

[Abstract] [PDF Full-Text (208 KB)] IEEE JNL

12 **DC-SQUIDS fabricated by electron beam direct writing**

Carelli, P.; Foglietti, V.; Leoni, R.;
Magnetics, IEEE Transactions on , Volume: 23 , Issue: 2 , Mar 1987
Pages:1087 - 1089

[Abstract] [PDF Full-Text (560 KB)] IEEE JNL

13 **Enhanced on-wafer time-domain waveform measurement through removal of interconnect dispersion and measurement instrument jitter**
Scott, J.B.; Verspecht, J.; Behnia, B.; Vanden Bossche, M.; Cognata, A.; Verbeyst, F.; Thorn, M.L.; Scherrer, D.R.;
Microwave Theory and Techniques, IEEE Transactions on , Volume: 50 , Issue: 12 , Dec. 2002
Pages:3022 - 3028

[Abstract] [PDF Full-Text (581 KB)] IEEE JNL

14 **A microneedle-based glucose monitor: fabricated on a wafer-level using in-device enzyme immobilization**
Zimmermann, S.; Fienbork, D.; Stoeber, B.; Flounders, A.W.; Liepmann, D.;
TRANSDUCERS, Solid-State Sensors, Actuators and Microsystems, 12th International Conference on, 2003 , Volume: 1 , 8-12 June 2003
Pages:99 - 102 vol.1

[Abstract] [PDF Full-Text (402 KB)] IEEE CNF

15 **Automated metrology qualification strategy [IC measurement]**

Chain, E.E.;
Advanced Semiconductor Manufacturing Conference and Workshop, 1996. ASMC 96 Proceedings. IEEE/SEMI 1996 , 12-14 Nov. 1996
Pages:337 - 342

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16 **Measurement of the linewidth of electrical test-structure reference features by automated phase-contrast image analysis**
am Ende, B.A.; Cresswell, M.W.; Allen, R.A.; Headley, T.J.; Guthrie, W.F.; Linholm, L.W.; Bogardus, E.H.; Murabito, C.E.
 Microelectronic Test Structures, 2002. ICMTS 2002. Proceedings of the 2002 International Conference on , 8-11 April 2002
 Pages: 1 - 6

[Abstract] [PDF Full-Text (391 KB)] IEEE CNF

17 **Calibration technique for MEMS membrane type strain sensors**
Li Cao; Tae Song Kim; Jia Zhou; Mantell, S.C.; Polla, D.L.
 University/Government/Industry Microelectronics Symposium, 1999. Proceedings of the Thirteenth Biennial , 20-23 June 1999
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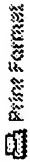
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18 **Thermoelectric microsensor for heat flux measurement**
Volklein, F.; Kessler, E.;
Thermoelectrics, 1998. Proceedings ICT 98. XVII International Conference on , May
24-28, 1998
Pages:214 - 217

[Abstract] [PDF Full-Text (280 KB)] IEEE CNF

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